

depositing a layer of tantalum pentoxide film directly overlaying and attaching to the metal film layer.

Please add new claim 15 as follows:

15. (New)

A method of manufacturing a thin film resistor with a moisture barrier comprising:

depositing a metal film layer on a substrate;

attaching a termination on each end of the metal film;

depositing a passivation layer directly overlaying and attaching to the metal film layer; and

depositing a layer of tantalum pentoxide film directly overlaying and attaching to the passivation layer.